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Bib Data Sheet

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| SERIAL NUMBER 10/712,594 | FILING DATE 11/12/2003 RULE | CLASS 438 | GROUP ART UNIT 2823 | ATTORNEY DOCKET NO. RYUKA.002AUS |
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APPLICANTS

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** CONTINUING DATA *****

This application is a CIP of PCT/JP02/04594 05/13/2002

YGS [Signature]

** FOREIGN APPLICATIONS *****

JAPAN JP2001-172645 06/07/2001
JAPAN JP2002-353141 12/04/2002

YGS [Signature]

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** 02/23/2004

| Foreign Priority claimed 35 USC 119 (a-d) conditions met | STATE OR COUNTRY JAPAN | SHEETS DRAWING 11 | TOTAL CLAIMS 27 | INDEPENDENT CLAIMS 7 |
|---|------------------------------|-------------------------|-----------------------|----------------------------|
| Yes <input checked="" type="checkbox"/> no <input type="checkbox"/> Met after Allowance Initials Examiner's Signature | | | | |

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TITLE

Electron beam exposure apparatus, electron beam exposing method, semiconductor element manufacturing method, and pattern error detection method

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| FILING FEE | FEES: Authority has been given in Paper | <input type="checkbox"/> All Fees |
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